



IN THE CLAIMS

Claims 1 – 35 (Cancelled)

36. (Currently amended) A method for moving a plurality of wafers, comprising:
positioning a plurality of ~~blades~~ end-effectors of a robotic hand adjacent an opening
of a first wafer receptacle having a plurality of wafers arrayed therein, wherein the plurality
of end-effectors also include a plurality of blades;

inserting the hand into the first wafer receptacle;
mechanically grasping a selected number of wafers by a corresponding number of
blades;
withdrawing the hand from the first wafer receptacle;
positioning the hand adjacent an opening of a second wafer receptacle;
inserting the hand into the second wafer receptacle; and
releasing the selected number of wafers into the second wafer receptacle.

37. (Original) The method of claim 36 wherein the selected number of wafers is one
of one, two, three, four, or five wafers.

38. (Currently amended) The method of claim 36, further comprising sensing the
presence of the selected number of wafers on the plurality of end-effectors in the first wafer
receptacle.

39. (Original) The method of claim 38 wherein sensing the presence and position of
the plurality of wafers comprises sensing a wafer peripheral zone proximate the hand.

40. (Currently amended) The method of claim 39 wherein sensing the presence and
position of wafer comprises detecting a displacement of a wafer contact pad when said wafer
contact pad contacts a wafer peripheral zone.

41. (Original) The method of claim 39 wherein optically sensing the wafer comprises
optically detecting a displacement of a wafer contact pad when said wafer contact pad
contacts a wafer peripheral zone.

42. (Currently amended) The method of claim 38 wherein sensing the presence and position of the plurality of wafers comprises optically sensing a wafer peripheral zone of each wafer proximate the hand.

43. (Original) The method of claim 36 wherein mechanically grasping a selected number of wafers comprises mechanically grasping each wafer only at a peripheral zone thereof.

44. (Original) The method of claim 36 wherein releasing the selected number of wafers comprises arraying the wafers in the second wafer receptacle.

45. (New) The method of claim 36 wherein the robotic hand is structured to retain one or more grasped wafers during multi-planar movement.